

Conference on LED and Its Industrial Application '14

LEDIA '14

Tuesday, April 22

15:30-15:45 Opening Room 411, 412

Opening Remarks

15:30 H. Amano, Conference Chair of LEDIA' 14
Nagoya Univ., Japan

15:45-16:45 LED1: GaN Bulk Growth Room 411, 412

Chair: Y. Mori, Osaka Univ., Japan

LED1-1 (Invited) Hydride Vapor Phase Epitaxy on Ammonothermally Grown GaN Seeds: Challenges and Perspectives
15:45

M. Boćkowski^{1,2)}
¹⁾ Institute of High Pressure Physics, PAS, Poland, ²⁾ Top GaN Sp. z o.o., Poland

LED1-2 Growth of GaN Layers Using Ga₂O Vapor Synthesized from Ga Metal
16:15

T. Sumi¹⁾, H. Takatsu¹⁾, M. Juta¹⁾, J. Y. Bu¹⁾, A. Kitamoto¹⁾, M. Imade¹⁾, M. Yoshimura¹⁾, M. Isemura²⁾, and Y. Mori¹⁾
¹⁾ Osaka Univ., Japan, ²⁾ Itochu Plastics Inc., Japan

LED1-3 Controlling the Growth Habit of Early Stage in the Na-Flux Coalescence Growth by the Dipping Technique
16:30

K. Nakamura, M. Imanishi, T. Sato, K. Murakami, H. Imabayashi, H. Takazawa, Y. Todoroki, D. Matsuo, M. Maruyama, M. Imade, M. Yoshimura, and Y. Mori
Osaka Univ., Japan

16:45-17:30 LED2 : Agricultural Applications Room 411, 412

Chair: Y. Mori, Osaka Univ., Japan

LED2-1 (Invited) Present Status of LED-Based Plant Factory in Japan
16:45

M. Takatsujii
Foundation of Social Development Research Center, Japan

LED2-2 Far-Red Cr-Doped Garnets for the Control of Photomorphogenesis in Plants Using Phosphor-Conversion LEDs
17:15

A. Zabiliūtė, S. Butkutė, A. Žukauskas, P. Vitta, and A. Kareiva
Vilnius Univ., Lithuania

Wednesday, April 23

9:00-12:00 LED3: UV Devices Room 411, 412

Chair: Y. Kumagai, Program Committee Chair,

Tokyo Univ. of Agri. & Tech., Japan

LED3-1 (Invited) Crystal Growth of AlN Single Crystal by Sublimation Method
9:00

S. Nagata
JFE Mineral Company, Ltd., Japan

LED3-2 (Invited) Recent Progress of AlGaIn UVC-LED by Improving Light-Extraction Efficiency
9:30

H. Hirayama

RIKEN, Japan

LED3-3 Reliability and Lifetime of Pseudomorphic UV-C LED Product for Instrumentation
10:00

M. Toita^{1,2)}, J. R. Grandusky¹⁾, J. Chen¹⁾, K. Kitamura^{1,2)}, M. C. Mendrick¹⁾, C. Moe¹⁾, Y. Li¹⁾, K. Nagase²⁾, T. Morishita³⁾, H. Ishii³⁾, S. Yamada³⁾, and L. J. Schowalter¹⁾

¹⁾ Crystal IS, U.S.A., ²⁾ Asahi Kasei, Japan, ³⁾ Asahi Kasei Microdevices, Japan

LED3-4 Nonpolar M-Plane AlGaIn Deep-UV LEDs
10:15

R. G. Banal, Y. Taniyasu, and H. Yamamoto
NTT Corp., Japan

----- Break (10:30-10:45) -----

Chair: H. Hirayama, RIKEN, Japan

LED3-5 Temperature Dependence of Deep Ultraviolet Emission for Diamond Light Emitting Diodes
10:45

D. Kuwabara¹⁻³⁾, T. Makino^{2,3)}, D. Takeuchi^{2,3)}, H. Kato^{2,3)}, M. Ogura^{2,3)}, H. Okushi^{2,3)}, and S. Yamasaki¹⁻³⁾

¹⁾ Univ. of Tsukuba, Japan, ²⁾ AIST, Japan, ³⁾ CREST, Japan

LED3-6 Investigation of Hole Injection in UV-LEDs Utilizing Polarization Effect
11:00

T. Yasuda¹⁾, K. Hayashi¹⁾, T. Nakashima¹⁾, T. Takeuchi¹⁾, S. Kamiyama¹⁾, M. Iwaya¹⁾, I. Akasaki^{1,2)}, and H. Amano^{2,3)}

¹⁾ Meijo Univ., Japan, ²⁾ Akasaki Research Center, Japan, ³⁾ Nagoya Univ., Japan

LED3-7 Optimization of InGaIn Superluminescent Diodes: State of the Art Devices and an Analysis of their Limiting Factors
11:15

A. Kafar¹⁾, S. Stanczyk¹⁾, G. Targowski^{2,3)}, P. Wisniewski¹⁾, T. Suski¹⁾, U. T. Schwarz⁴⁾, and P. Perlin^{1,2)}

¹⁾ Institute of High Pressure Physics, PAS, Poland, ²⁾ TopGaIn Sp. z o.o., Poland, ³⁾ Fraunhofer Institute for Applied Solid State Physics IAF, Germany, ⁴⁾ Freiburg Univ., Germany

LED3-8 The Impact of Al-Composition on Microstructures and Crystalline Quality of Semi-Polar Al_xGa_{1-x}N on GaAs Substrates by MOVPE Growth
11:30

P. Saengkaew¹⁾, S. Sanorpim²⁾, V. Yordsri³⁾, C. Thanachayanont³⁾, and K. Onabe⁴⁾

¹⁾ King Mongkut's Univ. of Technology North Bangkok, Thailand, ²⁾ Chulalongkorn Univ., Thailand, ³⁾ MTEC, Thailand, ⁴⁾ The Univ. of Tokyo, Japan

LED3-9 Optical Properties of Ga-In-O Polycrystalline Films Fabricated by Molecular Precursor Method
11:45

T. Onuma^{1,2)}, T. Yasuno²⁾, S. Takano²⁾, R. Goto²⁾, S. Fujioka²⁾, T. Hatakeyama²⁾, H. Hara²⁾, C. Mochizuki²⁾, H. Nagai²⁾, T. Yamaguchi²⁾, M. Sato²⁾, and T. Honda²⁾

¹⁾ Tokyo National College of Technology, Japan, ²⁾ Kogakuin Univ., Japan

----- Lunch Break (12:00-13:15) -----

13:15-18:00 LED4: InGaN Devices Room 411, 412

Chair: Y. J. Kim, Program Committee Member,
Yonsei Univ., Korea

LED4-1 (Invited) InGaN Light-Emitting Diodes on c-Face Sapphire Substrates in Green-Yellow Gap Spectral Region
13:15

S. Saito, R. Hashimoto, J. Hwang, and S. Nunoue
Toshiba Corp., Japan

LED4-2 (Invited) 740-nm InGaN-Based LEDs by MOVPE
13:45

K. Ohkawa
Tokyo Univ. of Science, Japan

LED4-3 Enhancement of Vertical Light Extraction from GaN-Based Blue LEDs Using Moth-Eye Patterned Sapphire Substrate
14:15

M. Ohya¹, K. Naniwae¹, T. Kondo¹, A. Suzuki¹, M. Mori¹, T. Kitano¹, and S. Kamiyama^{1,2}
¹ EL-Seed Corp., Japan, ² Meijo Univ., Japan

LED4-4 Investigation of InGaN Light-Emitting Diodes Prepared on High Aspect Ratio Patterned Sapphire Substrate with Sputtered AlN Nucleation Layer
14:30

L. C. Chang, Y. A. Chen, and C. H. Kuo
National Chiao Tung Univ., Taiwan

----- Break (14:45-15:00) -----

Chair: K. Ohkawa, Tokyo Univ. of Science, Japan

LED4-5 Roles of Mg Doping in Nitride Semiconductor-Based Light Emitting Diodes with Two Active Regions
15:00

K. Matsui¹, T. Morita¹, T. Suzuki¹, T. Takeuchi¹, S. Kamiyama¹, M. Iwaya¹, and I. Akasaki^{1,2}
¹ Meijo Univ., Japan, ² Akasaki Research Center, Japan

LED4-6 Diffusion Injected Multi-Quantum Well Light Emitting Diode Structure
15:15

L. Riuttanen, P. Kivisaari, H. Nykänen, O. Svensk, S. Suihkonen, J. Oksanen, J. Tulkki, and M. Sopanen
Aalto Univ., Finland

LED4-7 The Improvement of Efficiency Droop and Current Spreading on Nitride-Based LEDs Using Electron Transmission Layer
15:30

J. S. Jheng¹, C. K. Wang¹, Y. Z. Chiou¹, T. K. Lin², and S. J. Chang³
¹ Southern Taiwan Univ. of Science and Technology, Taiwan, ² Epistar Corp., Taiwan, ³ National Cheng Kung Univ., Taiwan

LED4-8 Growth of High Yield LED Structures on 8" Si(111) Substrates Using High throughput MOCVD Reactors
15:45

B. Krishnan, J. Su, S. M. Lee, G. D. Papasouliotis
Veeco Instruments Inc., U.S.A.

LED4-9 Surface Orientation Dependence of the In-Incorporation of THVPE-Grown InGaN Studied by First Principles and Statistical Thermodynamics
16:00

H. Murakami, Y. Fujimura, R. Togashi, Y.

Kumagai, and A. Koukitu
Tokyo Univ. of Agri. & Tech., Japan

LED4-10 Realization of p-Type Conduction in Mg-Doped N-Polar (0001) GaN Grown by Metalorganic Vapor Phase Epitaxy
16:15

T. Tanikawa^{1,2}, J. H. Choi^{1,2}, K. Shojiki¹, S. Kuboaya¹, R. Katayama^{1,2}, and T. Matsuoka^{1,2}
¹ Tohoku Univ., Japan, ² CREST, Japan

----- Break (16:30-16:45) -----

Chair: K. Naniwae, EL-Seed Corp., Japan
LED4-11 Growth Optimization of Green InGaN Multi-Quantum Well on Bulk GaN Substrate by in situ Monitoring System
16:45

T. Mitsunari¹, A. Tamura¹, S. Usami¹, M. Kushimoto¹, K. Yamashita¹, Y. Honda¹, Y. Lacroix³, and H. Amano^{1,2}
¹ Nagoya Univ., Japan, ² Akasaki Research Center, Japan, ³ YSystems Ltd., Japan

LED4-12 Evaluation of the Optical Polarization Properties in Semi-Polar {1122} LEDs
17:00

Y. Okamura, K. Nakao, N. Okada, K. Yamane, and K. Tadatomo
Yamaguchi Univ., Japan

LED4-13 Stress Compensated InGaN/AlGaN Superlattices Coherently Grown on Semipolar (1122) GaN Substrates
17:15

J. Nishinaka, M. Funato, and Y. Kawakami
Kyoto Univ., Japan

LED4-14 Relationship between V-Pit Diameter and Potential Barrier Height in InGaN Based Light-Emitting Diodes
17:30

N. Okada, M. Haziq, K. Yamane, Y. Yamada, and K. Tadatomo
Yamaguchi Univ., Japan

LED4-15 Suppression of Metastable-Phase Inclusion in MOVPE-Grown N-Polar (0001) InGaN/GaN Multiple Quantum Wells
17:45

K. Shojiki¹, J. H. Choi^{1,2}, T. Iwabuchi¹, N. Usami³, T. Tanikawa^{1,2}, S. Kuboaya¹, T. Hanada^{1,2}, R. Katayama^{1,2}, and T. Matsuoka^{1,2}
¹ Tohoku Univ., Japan, ² CREST, Japan, ³ Nagoya Univ., Japan

Thursday, April 24

9:00-9:45 LED5: White LEDs Room 411, 412

Chair: G. Hatakoshi, Program Committee Member,
Toshiba Corp., Japan

LED5-1 (Invited) Sialon Phosphors for Improved White LED
9:00

K. Takahashi^{1,2} and N. Hirosaki^{1,2}
¹ NIMS, Japan, ² SIALON Co., Ltd., Japan

LED5-2 High Brightness White LED Prepared by Silicone Layer-by-Layer Coatings with Uniform Distribution of
9:30

Quantum-Dot-Embedded Silica Nanoparticles
Y. J. Kim¹, H. G. Hong¹, H. S. Jung², H. J. Kim¹, M. H. Shin¹, H. Kim², and H. Lee²
¹ Yonsei Univ., Korea, ² Nanosquare Inc., Korea

----- Break (9:45-10:00) -----

10:00-11:45 LED6: Short Presentations for Poster Session
Room 411, 412

Chair: Y. Honda, Program Committee Member,
Nagoya Univ., Japan
T. Yamaguchi, Program Committee Member,
Kogakuin Univ., Japan
H. Murakami, Program Committee Member,
Tokyo Univ. of Agri. & Tech., Japan
R. Togashi, Program Committee Member,
Tokyo Univ. of Agri. & Tech., Japan

----- Lunch Break (11:45-13:15) -----

13:15-15:15 LED6: Poster Session Exhibition Hall D

LEDp6-1 Examination of on the Influence of Boron Flow Rate and Substrate in B GaN Epitaxial Growth
K.Ueyama, K. Atsumi, H. Mimura, Y. Inoue, T. Aoki, and T. Nakano
Shizuoka Univ., Japan

LEDp6-2 Rapid Growth of GaN Layers Using Ga₂O Vapor on GaN Substrates Grown by Na-Flux Method
H. Takatsu ¹⁾, M. Juta ¹⁾, T. Sumi ¹⁾, Y. Bu ¹⁾, A. Kitamoto ¹⁾, M. Imade ¹⁾, M. Yoshimura ¹⁾, M. Isemura ²⁾, and Y. Mori ¹⁾
¹⁾ Osaka Univ., Japan, ²⁾ Itochu Plastics Inc., Japan

LEDp6-3 Growth of High Crystallinity Thick GaN Layers Using Ga₂O Vapor
M. Juta ¹⁾, H. Takatsu ¹⁾, T. Sumi ¹⁾, Y. Bu ¹⁾, A. Kitamoto ¹⁾, M. Imade ¹⁾, M. Yoshimura ¹⁾, M. Isemura ²⁾, and Y. Mori ¹⁾
¹⁾ Osaka Univ., Japan, ²⁾ Itochu Plastics Inc., Japan

LEDp6-4 Growth of Homoepitaxial ZnO Thin Layers by Halide Vapor Phase Epitaxy Using Non-Hydrogenous Sources
R. Asakawa ¹⁾, Y. Isa ¹⁾, N. Kanzaki ¹⁾, S. Y. Kang ²⁾, A. Hiroe ²⁾, R. Togashi ¹⁾, H. Murakami ¹⁾, Y. Kashiwagi ²⁾, Y. Kumagai ¹⁾, and A. Koukitu ¹⁾
¹⁾ Tokyo Univ. of Agri. & Tech., Japan, ²⁾ Tokyo Electron Ltd., Japan

LEDp6-5 Fabrication of In-Doped ZnO Thin Film by Molecular Precursor Method
R. Goto, T. Yasuno, H. Nagai, H. Hara, M. Sato, and T. Honda
Kogakuin Univ., Japan

LEDp6-6 Thermal Stability of β -Ga₂O₃ Substrates in Mixed Flows of H₂ and N₂
C. Eguchi ¹⁾, T. Fukizawa ¹⁾, S. Hanagata ¹⁾, K. Nomura ¹⁾, K. Goto ²⁾, R. Togashi ¹⁾, H. Murakami ¹⁾, A. Kuramata ²⁾, Y. Kumagai ¹⁾, and A. Koukitu ¹⁾
¹⁾ Tokyo Univ. of Agri. & Tech., Japan, ²⁾ Tamura Corp. Ltd., Japan

LEDp6-7 C-Related p-Type Conduction in AlGaIn and AlN

LEDp6-8 InGaIn Growth on GaN/Sapphire by Increased-Pressure MOVPE
K. Yamashita ¹⁾, Y. Honda ¹⁾, and H. Amano ^{1,2)}
¹⁾ Nagoya Univ., Japan, ²⁾ Akasaki Research Center, Japan

LEDp6-9 Characterization of Dark Spots on GaInN Films by Using Fluorescence Microscope and Secondary Ion Mass Spectroscopy
N. Toyomitsu ¹⁾, L. Sang ²⁾, T. Yamaguchi ¹⁾, T. Honda ¹⁾, and M. Sumiya ²⁾
¹⁾ Kogakuin Univ., Japan, ²⁾ NIMS, Japan

LEDp6-10 High Efficiency GaN-Based LEDs Grown by Interruption-Free Epitaxial Lateral Overgrowth on Patterned SiO₂ AlN/Sapphire Template
Y. A. Chen, C. H. Kuo, L. C. Chang, and J. P. Wu
National Chiao Tung Univ., Taiwan

LEDp6-11 The Evaluation of Optical Characteristic of GaN Double Polarity Selective Area Growth by Using MOVPE
K. Kuze, Y. Fujita, H. Mimura, Y. Inoue, and T. Nakano
Shizuoka Univ., Japan

LEDp6-12 In Situ Wafer Temperature Measurement of Gallium Nitride Grown on Sapphire Using Diffuse Reflectance at Two Wavelengths
Y. Lacroix ¹⁾, K. Yamashita ¹⁾, V. Robichaud ¹⁾, Y. Majima ¹⁾, Y. Honda ²⁾, and H. Amano ²⁾
¹⁾ YSystems Ltd., Japan, ²⁾ Nagoya Univ., Japan

LEDp6-13 Effect of Pseudo Aluminum Templates in RF-MBE Growth of GaN on 4H-SiC
Y. Watanabe, S. Osawa, D. Tajimi, T. Yamaguchi, and T. Honda
Kogakuin Univ., Japan

LEDp6-14 Control of Surface Roughness of GaN Seed Crystals by Applying a Dipping Technique to the Na-Flux Method
T. Sato, M. Imanishi, K. Nakamura, K. Murakami, H. Imabayashi, H. Takazawa, Y. Todoroki, D. Matsuo, M. Maruyama, M. Imade, M. Yoshimura, and Y. Mori
Osaka Univ., Japan

LEDp6-15 The Relationship between Growth Habit and the Behaviors of Dislocations of GaN Crystals in the Na-Flux Coalescence Growth
M. Imanishi, K. Murakami, H. Imabayashi, H. Takazawa, Y. Todoroki, D. Matsuo, M. Maruyama, M. Imade, M. Yoshimura, and Y. Mori
Osaka Univ., Japan

LEDp6-16 High-Speed InN Growth on Yttria-Stabilized Zirconia (111) Substrates by a Two-Step Precursor Generation HVPE System
C. Kojima, R. Togashi, R. Imai, N. Fujita, H. Saito, H. Murakami, Y. Kumagai, and A. Koukitu
Tokyo Univ. of Agri. & Tech., Japan

LEDp6-17 Nanoscale Optical Analysis Using Cathodoluminescence Combined with Transmission Electron Microscopy
A. Maigne and D. J. Stowe
Gatan Inc., U.S.A.

- LEDp6-18 RF-MBE Growth of pn-GaN Structure and Fabrication of Blue-Green Homojunction-Type Light Emitting Diode**
K. Narutani ¹⁾, T. Yamaguchi ¹⁾, K. Wang ²⁾, T. Araki ²⁾, Y. Nanishi ²⁾, L. Sang ³⁾, M. Sumiya ³⁾, S. Fujioka ¹⁾, T. Onuma ^{1,4)}, and T. Honda ¹⁾
¹⁾ Kogakuin Univ., Japan, ²⁾ Ritsumeikan Univ., Japan, ³⁾ NIMS, Japan, ⁴⁾ Tokyo National College of Technology, Japan
- LEDp6-19 Efficiency Improvement of Nitride-Based Light-Emitting Diode with Physical Vapor Deposition AlN Nucleation Layer**
J. Lee ¹⁾, C. H. Yen ¹⁾, W. C. Lai ¹⁾, Y. Y. Yang ¹⁾, C. K. Wang ²⁾, and S. J. Chang ¹⁾
¹⁾ National Cheng Kung Univ., Taiwan, ²⁾ Southern Taiwan Univ. of Science and Technology, Taiwan
- LEDp6-20 Enhancement in Output Power of Blue Nitride-Based Light Emitting Diodes with an Electron Retarded Layer**
S. B. Chuang ¹⁾, C. K. Wang ¹⁾, Y. Z. Chiou ¹⁾, C. H. Yen ²⁾, W. C. Lai ²⁾, and S. J. Chang ²⁾
¹⁾ Southern Taiwan Univ. of Science and Technology, Taiwan, ²⁾ National Cheng Kung Univ., Taiwan
- LEDp6-21 High Current Density LED Performance on Low Dislocation Density GaN on Sapphire**
T. Sugiyama ¹⁾, K. Yamashita ²⁾, M. Iwai ¹⁾, Y. Honda ²⁾, T. Yoshino ¹⁾, and H. Amano ^{2,3)}
¹⁾ NGK Insulators, Ltd., Japan, ²⁾ Nagoya Univ., Japan, ³⁾ Akasaki Research Center, Japan
- LEDp6-22 Fabrication of InGaN Based Light-Emitting Diode Using Freestanding {20 2 1} GaN Substrate**
Y. Denpo, Y. Mitsui, K. Yamane, N. Okada, and K. Tadatomo
Yamaguchi Univ., Japan
- LEDp6-23 Nitride-Based Light Emitting Diodes with Buried Tunnel Junctions**
M. Ino ¹⁾, Y. Kuwano ¹⁾, T. Morita ¹⁾, D. Minamikawa ¹⁾, T. Takeuchi ¹⁾, S. Kamiyama ¹⁾, M. Iwaya ¹⁾, and I. Akasaki ^{1,2)}
¹⁾ Meijo Univ., Japan, ²⁾ Akasaki Research Center, Japan
- LEDp6-24 Fabrication of Vertical-Type GaN-Based Metal Oxide Semiconductor Light-Emitting Diodes**
S. Fujioka ¹⁾, T. Yasuno ¹⁾, A. Sato ¹⁾, T. Onuma ^{1,2)}, H. Nagai ¹⁾, T. Yamaguchi ¹⁾, M. Sato ¹⁾, and T. Honda ¹⁾
¹⁾ Kogakuin Univ., Japan, ²⁾ Tokyo National College of Technology, Japan
- LEDp6-25 Study of High-Reflective Ag-Based Electrode on p-Type GaN**
S. Kawai ¹⁾, D. Iida ¹⁾, M. Iwaya ¹⁾, T. Takeuchi ¹⁾, S. Kamiyama ¹⁾, and I. Akasaki ^{1,2)}
¹⁾ Meijo Univ., Japan, ²⁾ Akasaki Research Center, Japan
- LEDp6-26 Fabrication of Nitride-Based Blue LED with Eliminating Light-Absorptive Laser Scribing Damages**
S. Hanai ¹⁾, I. Nakatani ²⁾, A. Suzuki ^{1,3)}, T. Kitano ^{1,3)}, D. Iida ¹⁾, T. Kato ¹⁾, M. Iwaya ¹⁾, T. Takeuchi ¹⁾, S. Kamiyama ¹⁾, and I. Akasaki ^{1,4)}
¹⁾ Meijo Univ., Japan, ²⁾ Mitsubishi diamond industrial, Japan, ³⁾ EL-Seed Corp., Japan, ⁴⁾ Akasaki Research Center, Japan
- LEDp6-27 InGaN Flip-Chip Light-Emitting Diodes with Embedded Air Voids Grown on Selective-Area Ar-Implanted AlN/Sapphire Substrate**
Y. H. Yeh ¹⁾, J. K. Sheu ¹⁾, M. L. Lee ²⁾, C. J. Chang ²⁾, P. C. Chen ¹⁾, Y. C. Yang ¹⁾, C. H. Yen ¹⁾, W. C. Lai ¹⁾
¹⁾ National Cheng Kung Univ., Taiwan, ²⁾ Southern Taiwan Univ. of Science and Technology, Taiwan
- LEDp6-28 Auto-Split Laser Lift-Off Technique for Vertical-Injection GaN-Based Green Light-Emitting Diodes**
M. Chen ¹⁾, L. E. Cai ²⁾, J. Y. Zhang ¹⁾, L. Y. Ying ¹⁾, and B. P. Zhang ¹⁾
¹⁾ Xiamen Univ., China, ²⁾ Xiamen University of Technology, China
- LEDp6-29 Light-Emitting Diode Panel Lamps**
W. S. Cheung, Y. F. Cheung, and H. W. Choi
The Univ. of Hong Kong, Hong Kong
- LEDp6-30 Design Optimization of Pattern Structure for Improving Light Extraction Efficiency of Light-Emitting Diodes with Patterned Sapphire Substrate**
H. Cui and S. H. Park
Yeungnam Univ., Korea
- LEDp6-31 Numerical Study of the LEDs with Injected Current Modulated by Patterned Contact**
I. Khmyrova ¹⁾, N. Watanabe ¹⁾, Ju. Kholopova ²⁾, A. Kovalchuk ²⁾, and S. Shapoval ²⁾
¹⁾ Univ. of Aizu, Japan, ²⁾ IMT RAS, Russia
- LEDp6-32 Phosphor-Converted Light-Emitting Diodes with Advanced Color Rendition Properties**
A. Zabiliūtė, R. Vaicekauskas, P. Vitta, A. Tuzikas, A. Petrulis, and A. Žukauskas
Vilnius Univ., Lithuania
- LEDp6-33 Control of Thickness and Concentration of Color Converting Film Based on Quantum Dots for White LED with High Luminous Efficiency and CRI**
H. J. Kim, M. H. Shin, H. G. Hong, and Y. J. Kim
Yonsei Univ., Korea
- Break (15:15-15:30) -----
- 15:30-16:30 LED7: Special Lectures** Room 411, 412
- Chair: M. Boćkowski,**
Institute of High Pressure Physics, PAS, Poland, Top GaN Sp. z o.o., Poland
- LED7-1 Fundamentals and Integration Technologies for Semiconductor Light-Emitting Devices**
15:30
H. Yonezu (Under negotiation)
Toyohashi Univ. of Tech., Japan
- LED7-2 Red and Blue LEDs: Physics and Applications of Visible Light Emitting Diodes**
16:00
G. Hatakoshi
Toshiba Corp., Japan
- 16:30-16:45 Closing** Room 411, 412

Closing Remarks

16:30 Y. Kumagai, Program Committee Chair
Tokyo Univ. of Agri. & Tech., Japan